



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Group Art Unit: 1765

Examiner: CHEN, Kin Chan

RESPONSE

Inventor:

BELLMAN, et al.

Serial No:

10/722,769

Filing Date:

November 26, 2003

Title:

METHOD USING MULTI-

COMPONENT COLLOIDAL

ABRASIVES FOR CMP

PROCESSING OF

SEMICONDUCTOR AND OPTICAL MATERIALS

Mail Stop Amendment Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

RESPONSE TO THE EXAMINER'S RESTRICTION REQUIREMENT

In response to the Office Action dated March 3, 2005 in the above-captioned application, please enter the following Amendments and Remarks.

Amendment to the specification begins at page 2 in this paper.

Amendments to the claims begin at page 3 in this paper.

Remarks begin on page 7 in this paper.